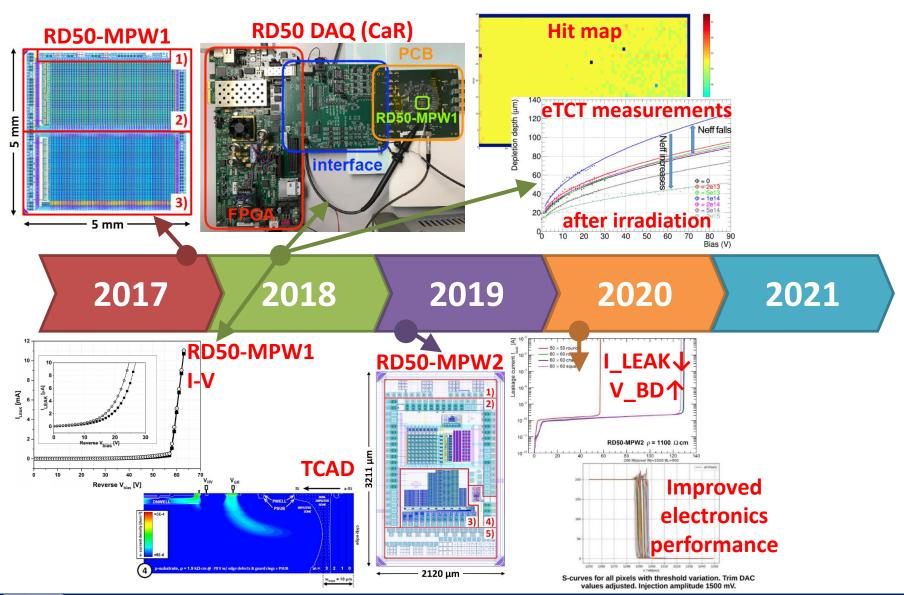
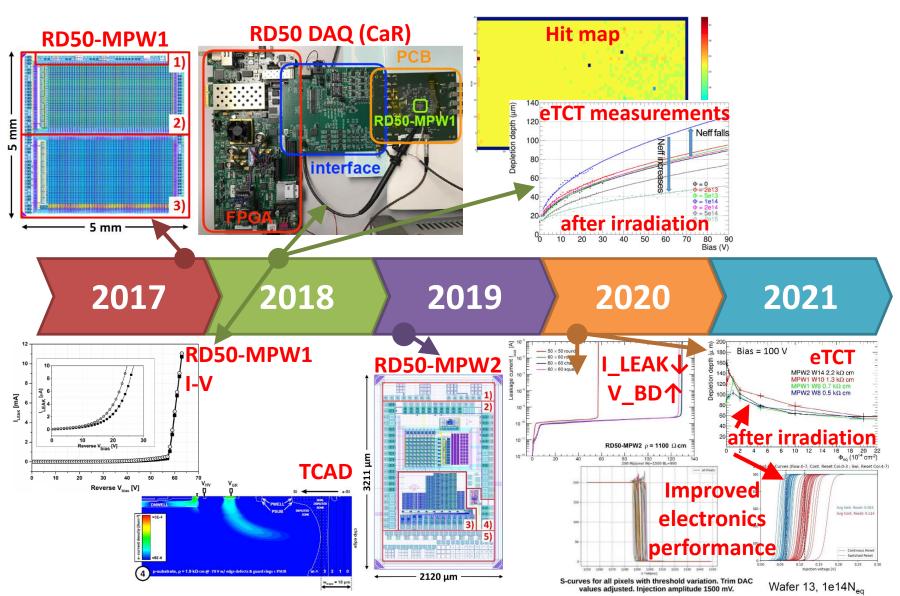


RD50 CMOS timeline



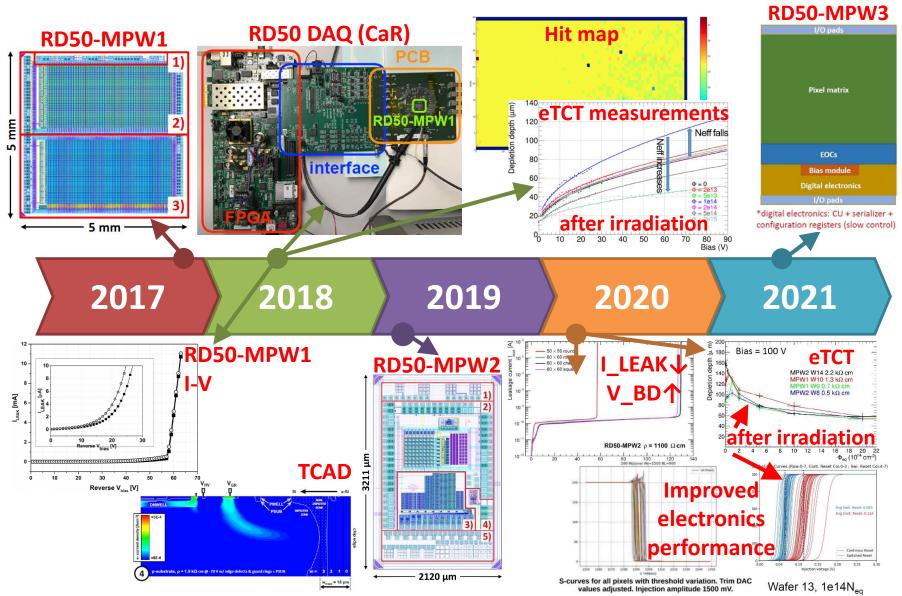


RD50 CMOS timeline





RD50 CMOS timeline





RD50 CMOS – Where are we?

- After a difficult start, we are now in the right direction
- RD50-MPW2 performs very nicely
 - Despite coronavirus and subsequent lockdowns, we have lots of interesting results
 - We expect to have many more results in the near future
 - Test beam
 - Accurate time resolution measurements
 - SEE and CCE measurements
- We are doing design work towards our next chip submission (RD50-MPW3)
 - Matrices of pixels
 - FE-I3 style matrix with highly improved readout electronics, especially those at the periphery to make data taking easier
 - Small sensor diodes matrix To study new sensor cross-sections
 - Sampling matrix To further improve sensor time resolution
 - The chip will incorporate all the lessons learned with RD50-MPW1/2
 - Small pixels with analogue and digital readout electronics
 - Methods to optimise I LEAK and V BD developed for RD50-MPW2
 - The chip submission will be in Q2 2021 (funding request in Q1 2021)





RD50 CMOS – Milestones

RD50 prolongation request – May 2018

- M1: Characterization of the diodes and readout electronics of unirradiated and irradiated RD50-MPW1 samples (Q4/2018) → <u>Achieved</u>
 - M1.2 (new): Design and submission of RD50-MPW2 (Q1/2019) →
 Achieved
 - M1.3 (new): Characterization of unirradiated and irradiated RD50-MPW2 samples (Q1+Q2/2020) → Ongoing
 - M1.4 (new): Design and submission of RD50-MPW3 (Q2/2021) →
 Ongoing
- M2: Design and submission for fabrication of RD50-ENGRUN1 (Q4/2018)
- M3: Characterization of unirradiated and irradiated RD50-ENGRUN1 samples (Q3/2019, Q3/2020)
- M4: Characterization of irradiated backside biased RD50-ENGRUN1 samples for operation beyond 10^{16} n_{eq}/cm (Q4/2020)
- M5: Studies of stitching process options (Q4/2021)
- M6: Characterization of unirradiated and irradiated stitched samples (Q4/2022)